## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Continuation of Daniel J.C. Herr et al;

Application No. not yet assigned

Filed: currently herewith

For: PATTERNING METHODS AND SYSTEMS USING REFLECTED

**INTERFERENCE PATTERNS** 

Date: March 9, 2004

Mail Stop PATENT APPLICATION Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

## INFORMATION DISCLOSURE STATEMENT

Sir:

Attached is a list of documents on form PTO-1449. Items 1-34 listed on the PTO-1449 were cited in parent application Serial No. 09/781,881, filed February 12, 2001. As the benefit of this application is claimed under 35 U.S.C. §120, no copies need to be furnished in accordance with 37 C.F.R. §1.98(d); however, copies will be furnished on request. It is requested that these documents be considered by the Examiner and officially made of record in accordance with the provisions of 37 C.F.R. §1.56 and Section 609 of the MPEP.

No fee is believed due. However, the Commissioner is hereby authorized to charge any deficiency or credit any overpayment to Deposit Account No. 50-0220.

Respectfully submitted,

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APPLICATION, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

Joyce Paoli

Substitut	te form 1449A	/PTO		Complete if Known		
				Application Number	not yet assigned	
INFORMATION DISCLOSURE				Filing Date	concurrently herewith	
STATE	STATEMENT BY APPLICANT			First Named Inventor	Daniel J.C. Herr	
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Sheet	1	of	2	Attorney Docket Number	5347-204CT	

			U.S. PATENTS	AND PATENT PUBLICATIONS	-
Examiner Initials*	Cite No.	U.S. Patent Document		Name of Patentee or Applicant of Cited	Date of Publication of Cited
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Examiner	Cite	OTHER NON PATENT LITERATURE DOCUMENTS  Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal,	T					
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